FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE (REV. 2-32) PATENT AND TRADEMARK OFFICE

ATTY. DOCKET NO. 47265.27 SERIAL NO. 10/560,122

APPLICANT Manfred Faubel, et al.

STATEMENT BY APPLICANT
Customer Number; 23973

FILING DATE 8 December 2005 (371 date) ART UNIT 2882
Not Yet Assigned

سنون	U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	No.	DOCUMENT NUMBER	ISSUE/PUB DATE	NAME	CLAS S	SUB- CLAS S	FILING DATE or PRIORITY DATE
/ACH/	AA	6447553 B1	10SEP2002	MIKHAEL, ET AL			24OCT2000
/ACH/	AB	6377651 B1	23APR2002	RICHARDSON, ET AL			10OCT2000
/ACH/	AC	6324255 B1	27NOV2001	KONDO, ET AL			12AUG1999
/ACH/	AD	6133577	17OCT2000	GUTOWSKI, ET AL			4FEB1997
/ACH/	AE	5459771	17OCT1995	RICHARDSON, ET AL			1APR1994

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	Name of Patentee or Applicant	Countr	Date of Publication of Cited Document	TRANSLATIO YES NO	
/ACH/	AF	WO 02/072279 A1	JOSEF SCHIELE OHG	wo	19SEP2002	ABSTRACT	
/ACH/	AG	WO 97/40650	HANS M. HERTZ	WO	30OCT1997		
/ACH/	AH	EP 1367445 A1	NORTHROP GRUMMAN CORPORATION	EP	12MAR2003		
/ACH/	AI	EP 0186491 A2	KABUSHIKI KAISHA TOSHIBA	EP	7FEB1986		
/ACH/	AJ	DE 10233634 A1	MAX-PLANCK-GESELLSCHAFT AND GEORG-AUGUST- UNIVERSITAT	EP	4MAR2004	SUMMARY	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

OTHE	R DOCU	MENTS (Including Author, Title, Date, Pertinent Pages, Etc.)
/ACH/	AK	RYMELL, L. et al.; "Debris elimination in a droplet-target laser-plasma soft x-ray source", Rev. Sci. Instrum., October 1995, Vol. 66, No. 10, pp 4916-4920.
/ACH/	AL	MALMQVIST, L., et al.; "Droplet-target laser-plasma source for proximity x-ray lithography", Appl. Phys. Lett., 6 May 1996, Vol. 68, No. 19, pp 2627-2629.
/ACH/	AM	HANSSON, BJÖRN A.M., et al.; "Status of the liquid-xenon-jet laser-plasma source for EUV lithography", Proceedings of SPIE, 2002, Vol. 4688, pp 102-109.
/ACH/	AN	STRUTT, John William, 3rd Baron Rayleigh; "On the Capillary Phenomena of Jets, (Proceedings of the Royal Society, 1879)", Scientific Papers, 1869-1881, Vol. 1, pp 377-400.
/ACH/	AO	WILSON, Kevin R., et al.; "X-ray Spectroscopy of Liquid Water Microjets", J. Phys. Chem. B, 2001, Vol. 105, No. 17, pp 3346-3349.
/ACH	AP	BOBASHEV, Sergei V., et al.; "Diagnostic technique of gas jet for debris-free laser-plasma EUV source", Proceedings of SPIE, 2000, Vol. 3997, pp 777-783.
/ACH/	AQ	HANSSON, BJÖRN A.M., et al.; "Liquid-Xenon-Jet Laser-Plasma Source for EUV Lithography" Proceedings of SPIE 2001, Vol. 4506, pp. 1-8

/Allen C. Ho/

05/04/2011